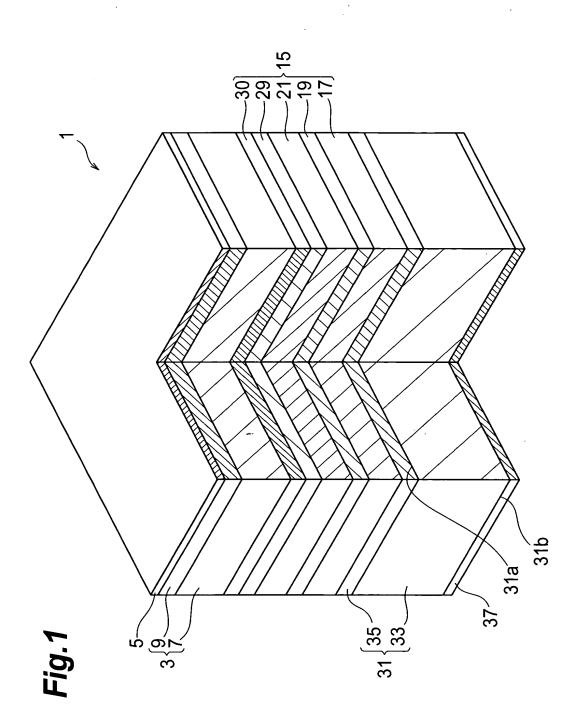
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Fig.2A

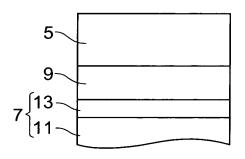
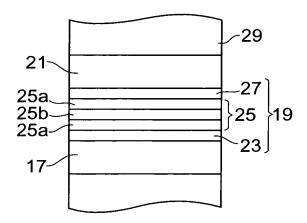


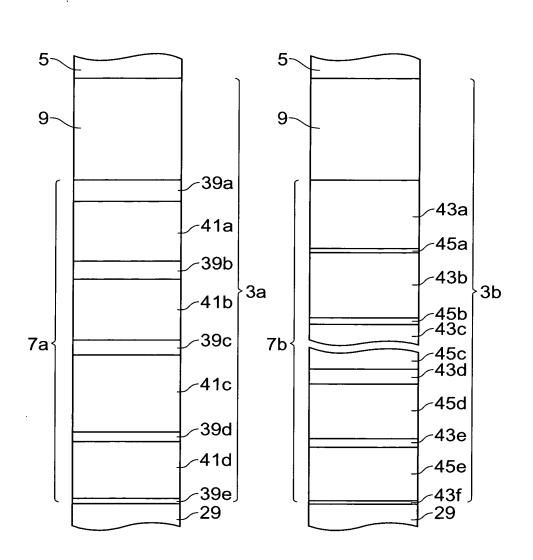
Fig.2B



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Fig.3B



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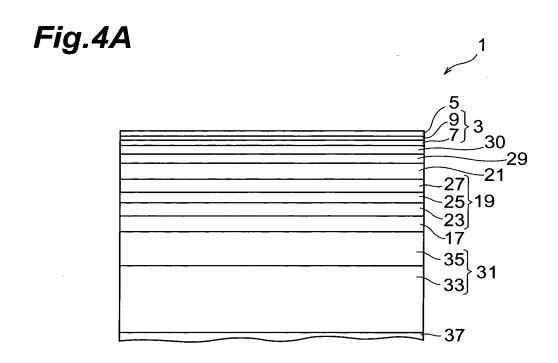
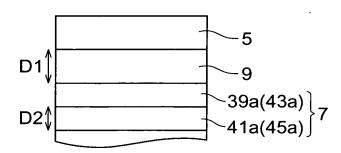


Fig.4B

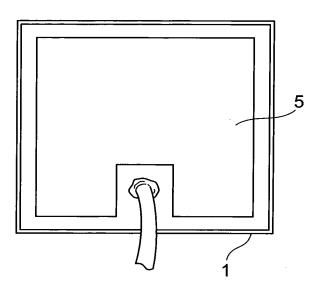


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Fig.5



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Fig.6A

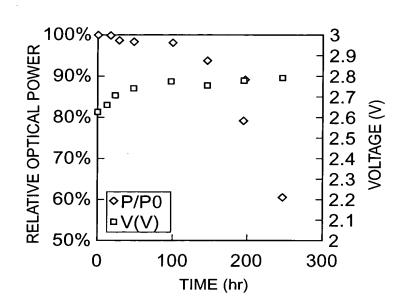
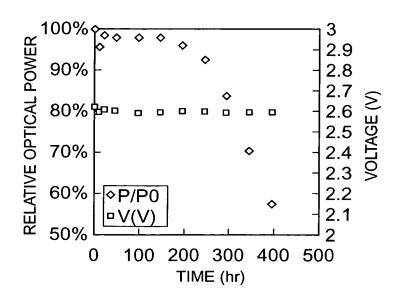


Fig.6B

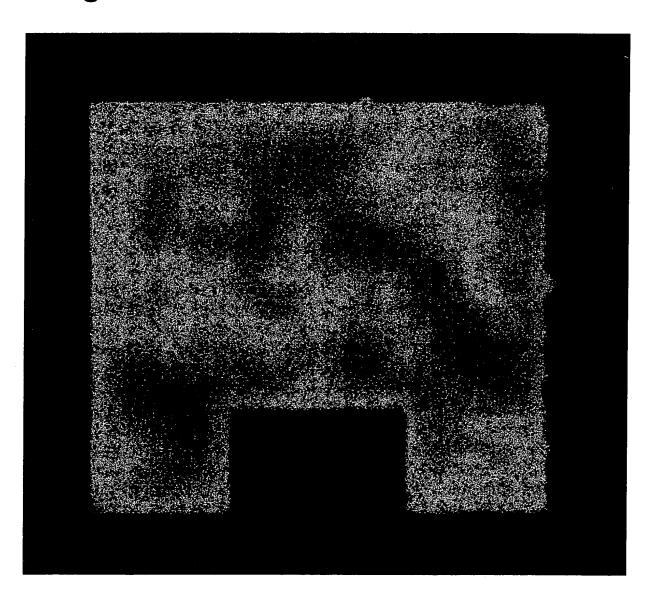


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Fig.7



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Fig.8A

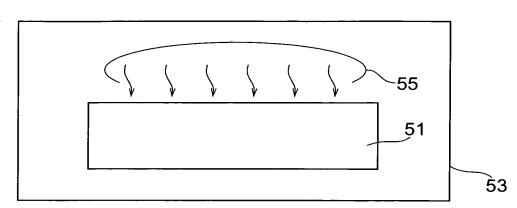


Fig.8B

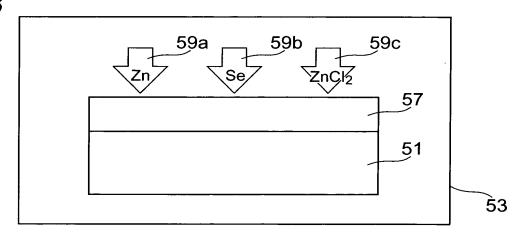
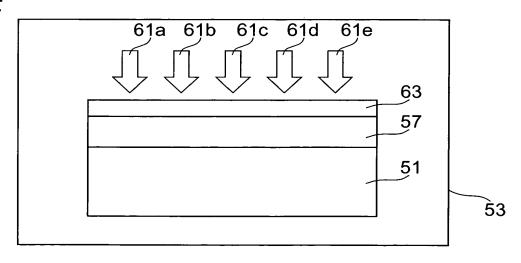
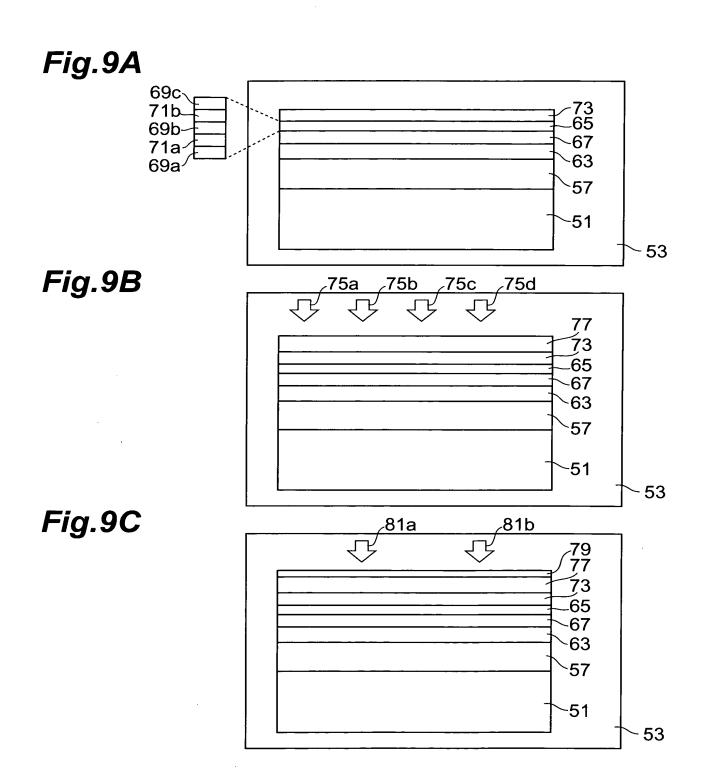


Fig.8C



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Fig.10A

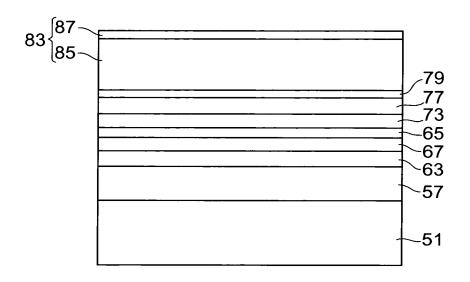
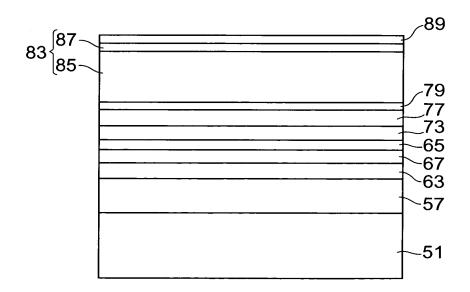


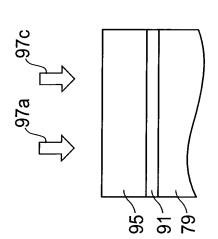
Fig.10B



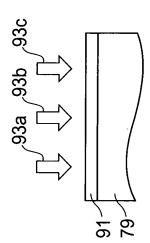
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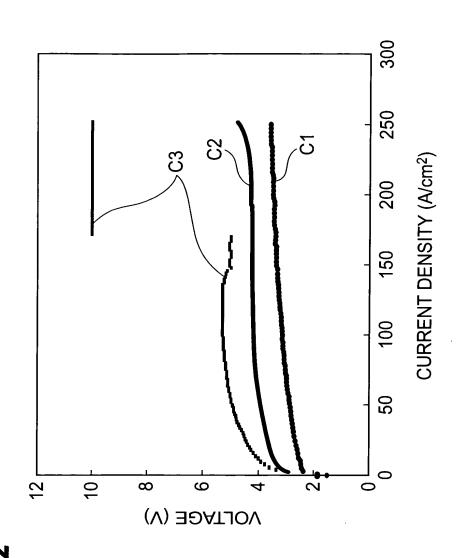
Fig.11A







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